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Title: CAUSE TO EFFECT
METHODOLOGY FOR
MONITORING
DATABASE
PERFORMANCE

Examiner: 5760-14800

Group/Art Unit: Rayyan, Susan F.

Atty. Dkt. No: 2167

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/ B. Noël Kivlin / October 4, 2007
Signature Date

Commissioner for Patents
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This paper is submitted in response to the Office Action of June 4, 2007, to further highlight why the application is in condition for allowance.

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